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IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

In re application of

: Confirmation No. 7681

Akihisa HONGO et al.

: Docket No. 2001_0519A

Serial No. 09/842,650

: Group Art Unit 1763

Filed April 27, 2001

: Examiner S. Macarthur

REVOLUTION MEMBER SUPPORTING
APPARATUS AND SEMICONDUCTOR
SUBSTRATE PROCESSING APPARATUS

: Mail Stop: AF

**RESPONSE UNDER 37. CFR 1.116
EXPEDITED PROCEDURE
EXAMINING GROUP 1763**

AMENDMENT AFTER FINAL OFFICE ACTION

Commissioner for Patents
P.O. Box 1450
Alexandria, VA 22313-1450

THE COMMISSIONER IS AUTHORIZED
TO CHARGE A DEFICIENCY IN THE
FEES FOR THIS PAPER TO DEPOSIT
ACCOUNT NO. 23-0975

Sir:

In response to the Office Action of May 20, 2004, please amend the above-identified U.S.
Patent application as follows: